



2814

PATENT

Case Docket No. ASMEX.367A
Date: September 26, 2003

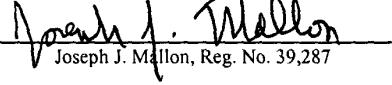
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Michael A. Todd
Appl. No. : 10/074,534
Filed : February 11, 2002
For : PROCESS FOR DEPOSITION
OF SEMICONDUCTOR FILMS
Examiner : Shrivinas H. Rao
Group Art Unit : 2814

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

September 26, 2003

(Date)


Joseph J. Mallon

Joseph J. Mallon, Reg. No. 39,287

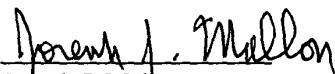
TRANSMITTAL LETTER

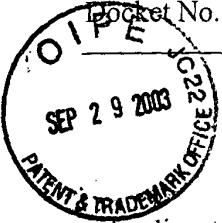
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) An Information Disclosure Statement.
- (X) A PTO Form 1449 with one (1) references.
- (X) The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 11-1410.
- (X) Return prepaid postcard.


Joseph J. Mallon
Registration No. 39,287
Attorney of Record
Customer No. 20,995
(619) 235-8550

**INFORMATION DISCLOSURE STATEMENT**

Applicant : Michael A. Todd
App. No. : 10/074,534
Filed : February 11, 2002
For : PROCESS FOR DEPOSITION OF SEMICONDUCTOR FILMS
Examiner : Shrivinas H. Rao
Group Art Unit : 2814

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing one (1) reference that is also enclosed.

This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(3). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 9/26/03

By: Joseph J. Mallon
Joseph J. Mallon
Registration No. 39,287
Attorney of Record
Customer No. 20,995
(619) 235-8550



FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. ASMEX.367A	APPLICATION NO. 10/074,534
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		APPLICANT Michael A. Todd	
(USE SEVERAL SHEETS IF NECESSARY)		FILING DATE February 11, 2002	GROUP 2814

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)

FOREIGN PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
	Todd, Michael A. et al., "Deposition of Si 1-x Ge x Films for Gate Electrode Applications Using a Novel Approach," ICSI3, The SiGe Conference; Santa Fe, NM, March 2003

S:\DOCS\JOM\JOM-5285.DOC:092603

EXAMINER	DATE CONSIDERED
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	